

# **INVESTIGATION OF ULTRASONIFICATION EFFECT ON PHYSICAL AND ELECTRICAL** CHARACTERISTICS OF Bax Sr1-x TiO3 THIN FILMS **PREPARED USING SOL-GEL METHOD**

by

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# **School of Microelectronic Engineering UNIVERSITI MALAYSIA PERLIS**

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# **TABLE OF CONTENTS**

# PAGES

DECLARATION OF THESIS	ii
COPYRIGHT	, X iii
ACKNOWLEDGEMENTS	iv
TABLE OF CONTENTS	v
LIST OF TABLES	ix
LIST OF FIGURES	Х
LIST OF ABBREVIATIONS	xiii
LIST OF SYMBOLS	XV
ABSTRAK	xvi
ABSTRACT	xvii
-0×	

# CHAPTER ONE: INTRODUCTION

1.1	Research introduction	1
1.2	Overview of barium strontium titanate	1
1.3	Research problem	3
1.4	Research objectives	5
1.5	Research scope	6
1.6	Research approach	6
1.7	Thesis organization	8

# CHAPTER TWO: LITERATURE REVIEW

2.1	Introduction	9
2.2	Dielectric	9

2.3	Ferroelectricity	11
2.4	Characteristics of barium strontium titanate	14
2.5	Preparation techniques of $Ba_x Sr_{1-x} TiO_3$ thin films	16
2.6	Ultrasonification	19
2.7	Platinum as the bottom electrode for capacitor design	20
2.8	Previous works on $Ba_x Sr_{1-x} TiO_3$ thin films	21
2.9	Summary	26

CHAPTER 7	THREE: RESEARCH METHODOLOGY	
3.1	Overview	28
3.2	Process steps of producing Bax Sr <sub>1-x</sub> TiO <sub>3</sub>	29
3.3	Solution preparation and deposition process of $Ba_x Sr_{1-x} TiO_3$	31
	3.3.1 Sol-gel method (without using ultrasonic)	31
	3.3.2 Preparation of sol-gel using ultrasonic method	33
	3.3.3 Cross section layer of $Ba_x Sr_{1-x} TiO_3$	34
	3.3.4 Mass-mole calculation	35
3.4	Wafer preparation	37
	3.4.1 Wafer cleaning process	38
	3.4.2 Dry oxidation (SiO <sub>2</sub> ) process	38
	3.4.3 Platinum sputtering process	39
3.5	Solution deposition process	40
	3.5.1 Spin coating	41
	3.5.2 Heat treatment process	41
3.6	Physical characterization of $Ba_x Sr_{1-x} TiO_3$ thin films	42
	3.6.1 Confirmation phase formation using X-ray diffraction	43
	(XRD)	
	3.6.2 Physical characterization of the thin films	45
	3.6.3 Thickness measurement of $Ba_x Sr_{1-x} TiO_3$	46
3.7	Capacitor structure of the $Ba_x Sr_{1-x} TiO_3$ thin films	47
	3.7.1 Electrical characterization of $Ba_x Sr_{1-x} TiO_3$ thin films	49

# CHAPTER FOUR: RESULTS AND DISCUSSIONS

4.1	Overv	riew	50
4.2	X-ray	diffraction	51
	4.2.1	Introduction	51
	4.2.2	Crystallinity of Ba <sub>0.6</sub> Sr <sub>0.4</sub> TiO <sub>3</sub> films	52
	4.2.3	XRD analysis of $Ba_{0.8}$ Sr <sub>0.2</sub> TiO <sub>3</sub> films	55
	4.2.4	BST film X-Ray diffraction analysis	58
	4.2.5	Effect of deposition temperature on crystallinity of BST	61
	4.2.6	Summary	64
4.3	Atom	ic Force Microscope (AFM)	65
	4.3.1	Introduction	65
	4.3.2	2D and 3D topographic surface analysis	66
		4.3.2.1 2D topographic surface analysis	67
		4.3.2.2 3D topographic surface analysis	68
	4.3.3	Root-Mean-Square (RMS) surface roughness analysis	71
	4.3.4	BST grain size analysis	73
	4.3.5	Summary	75
4.4	Thicknes	ss measurement of BST films	76
4.5	Dielectri	c properties of Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub>	78
	4.5.1	Current density of Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub>	79
O'Y	4.5.2	Dielectric constant and tunability of $Ba_x Sr_{1-x} TiO_3$	81

# CHAPTER FIVE: CONCLUSION AND RECOMMENDATION

5.1	Introduction	88
5.2	Conclusion	89
5.3	Recommendation for future work	92

REFERENCES	93
LIST OF PUBLICATIONS	100
APPENDIX A	101
APPENDIX B	103
APPENDIX C	104
APPENDIX D	105

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# LIST OF TABLES

TITLE	PAGE
Quantities of materials used in Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub> preparation	31
Summary of XRD results on the samples for Ba <sub>0.6</sub> Sr <sub>0.4</sub> TiO <sub>3</sub>	54
Summary of XRD results on the samples for Ba <sub>0.8</sub> Sr <sub>0.2</sub> TiO <sub>3</sub>	57
Two-dimensional AFM surface analysis images for two	67
preparation methods of $Ba_x Sr_{1-x} TiQ_3$	
Average RMS values of BST samples	72
Average grain size analysis values of BST samples	73
Average thickness values of BST samples	77
Effects of thickness and grain size on the dielectric constant and	83
tunability tec ternis protections	
	TTTLE Quantities of materials used in Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub> preparation Summary of XRD results on the samples for Ba <sub>0.6</sub> Sr <sub>0.2</sub> TiO <sub>3</sub> Summary of XRD results on the samples for Ba <sub>0.8</sub> Sr <sub>0.2</sub> TiO <sub>3</sub> Two-dimensional AFM surface analysis images for two preparation methods of Ba <sub>x</sub> Sr <sub>1-x</sub> TiO <sub>3</sub> Average RMS values of BST samples Average grain size analysis values of BST samples Effects of thickness and grain size on the dielectric constant and tunability

# LIST OF FIGURES

# FIGURE

# TITLE

# PAGE

Figure 2.1	Schematic representation of dielectric polarization.	11
Figure 2.2	Phase transitions of ferroelectric due to temperature	12
Figure 2.3	A typical ferroelectric hysteresis loop	13
Figure 2.4	Perovkite (ABO <sub>3</sub> ) structure	14
Figure 3.1	Summary of the whole process steps	30
Figure 3.2	Detailed flow chart for preparation of BST solution and thin films	32
	using sol-gel with and without involving ultrasonic methods.	
Figure 3.3	Cross section layer of sample	34
Figure 3.4	Flow chart of wafer preparation and cleaning	37
Figure 3.5	Cross section of the sample for BST deposition process	40
Figure 3.6	Annealing schedule using furnace	42
Figure 3.7	BST solution turned to white after 2 weeks.	43
Figure 3.8	Cross section of the XRD samples	44
Figure 3.9	Five points for the average measurement (top view)	46
Figure 3.10	Complete fabrication process of BST capacitor	48
Figure 4.1	XRD patterns of BST films grown on Si/SiO <sub>2</sub> /Pt substrate	53
	(involving ultrasonic) with the ratio of 60:40, annealed at $800^{\circ}$ C	
	for 2 hours.	
Figure 4.2	XRD patterns of BST films grown on Si/SiO <sub>2</sub> /Pt substrate	53
	(without involving ultrasonic) with the ratio of 60:40, annealed at	
	800°C for 2 hours.	
Figure 4.3	XRD patterns of BST films grown on Si/SiO <sub>2</sub> /Pt substrate	56
	(involving ultrasonic) with the ratio of 80:20, annealed at $800^{\circ}$ C	
	for 2 hours.	

Figure 4.4	XRD patterns of BST films grown on Si/SiO <sub>2</sub> /Pt substrate	56
	(without involving ultrasonic) with the ratio of 80:20, annealed at	
	800°C for 2 hours.	
Figure 4.5	XRD patterns of BST films grown on Si/SiO <sub>2</sub> /Pt substrates,	58
	annealed at 800°C for 2 hours: (A) BST 60:40 (involving	
	ultrasonic); (B) BST 60:40 (without involving ultrasonic); (C)	
	BST 80:20 (involving ultrasonic); (D) BST 80:20 (without	
	involving ultrasonic).	
Figure 4.6	BST (110) Diffraction peaks for (A) BST 60:40 (involving	59
	ultrasonic); (B) BST 60:40 (without involving ultrasonic); (C)	
	BST 80:20 (involving ultrasonic); (D) BST 80:20 (without	
	involving ultrasonic)	
Figure 4.7	XRD patterns of BST films annealed at different temperature;	60
	600°C, 700°C, 800°C (Hong Zhu et al., 2001).	
Figure 4.8	XRD patterns of BST films grown on Si/SiO2 substrate (involving	62
	ultrasonic) with the ratio of 60:40, annealed at $700^{\circ}$ C for 2 hours.	
Figure 4.9	XRD patterns of BST films grown on Si/SiO <sub>2</sub> substrate (without	62
	involving ultrasonic) with the ratio of 60:40, annealed at $700^{\circ}$ C	
	for 2 hours.	
Figure 4.10	Corresponding three-dimensional AFM surface analysis image for	69
•	BST 60:40, (sol-gel method involving ultrasonic) annealed at	
< n	800°C	
Figure 4.11	Corresponding three-dimensional AFM surface analysis image for	69
	BST 60:40, (sol-gel method without involving ultrasonic)	
	annealed at 800°C	
Figure 4.12	Corresponding three-dimensional AFM surface analysis image for	70
	BST 80:20, (sol-gel method involving ultrasonic) annealed at	
	800°C	
Figure 4.13	Corresponding three-dimensional AFM surface analysis image for	70
	BST 80:20, (sol-gel method without involving ultrasonic)	
	annealed at 800°C	

Figure 4.14	RMS roughness vs Method of preparation	72
Figure 4.15	Average grain size vs Method of preparation	73
Figure 4.16	Surface profiler software interface	76
Figure 4.17	Average thickness vs Method of preparation	77
Figure 4.18	Leakage current density as a function of voltage characteristic of	80
	BST films; (A) BST 60:40 (involving ultrasonic); (B) BST 60:40	
	(without involving ultrasonic); (C) BST 80:20 (involving	
	ultrasonic); (D) BST 80:20 (without involving ultrasonic)	
Figure 4.19	Electric field dependence of the $\varepsilon_r$ for the BST thin films; (A)	82
	BST 60:40 (involving ultrasonic); (B) BST 60:40 (without	
	involving ultrasonic); (C) BST 80:20 (involving ultrasonic); (D)	
	BST 80:20 (without involving ultrasonic).	
Figure 4.20	Film thickness dependence of the e and tunability for the BST	84
	thin films; (a) BST 60:40 (involving and without involving	
	ultrasonic); (b) BST 80:20 (involving and without involving	
	ultrasonic)	
Figure 4.21	Grain size dependence of the $\varepsilon_r$ and tunability for the BST thin	86
	films; (a) BST 60:40 (involving and without involving ultrasonic);	
	(b) BST 80:20 (involving and without involving ultrasonic).	
Figure 4.22	Tunability and $\varepsilon_r$ as a function of Ba content and preparation	87
• (	method; (a) BST 60:40 (involving and without involving	
1/1	ultrasonic); (b) BST 80:20 (involving and without involving	
$\odot$	ultrasonic)	

# LIST OF ABBREVIATIONS

BST	=	Barium Strontium Titanate
XRD	=	X-ray Diffraction
AFM	=	Atomic Force Microscope
SPA	=	Semiconductor Parameter Analyzer
DIW	=	De-ionized Water
CSD	=	Chemical Solution Deposition
RMS	=	Root-Mean-Square
Al	=	Aluminium
Pt	=	Platinum
RTA	=	Rapid Thermal Annealing
SPM	=	Scanning Probe Microscopes
GaN	=	Gallium Nitride
PVD	=	Physical Vapour Deposition
Sr	=	Strontium
Si	=	Silicon
SiO <sub>2</sub>	=	Silicon dioxide
BaTiO <sub>3</sub>		Barium titanate
PZT	=	Zirconate titanate and
STO 🛈	=	Strontium titanate
TCD	=	Temperature coefficient of dielectric constant
MOCVD	=	Metal organic chemical vapor deposition
PbTiO <sub>3</sub>	=	Lead Titanate
PTC	=	Positive temperature coefficcient
CVD	=	Chemical Vapor Deposition
PECVD	=	Plasma Enhance Chemical Vapor Deposition
MOD	=	Metallorganic Decomposition
DRAM	=	Dynamic random-access memory

LSMCD =	Liquid source i	misted chemical	deposition
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TEM = Transmission Electron Microsco	ope
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- Capacitance Voltage C-V =
- P-E Polarization-electric field =
- Argentum Ag =
- RF Radio frequency =
- MgO Magnesium Oxide =
- I-V

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# LIST OF SYMBOLS

V	=	Volts
ε <sub>r</sub>	=	Dielectric constant
d	=	Film thickness
С	=	Capacitance
А	=	Area in m <sup>2</sup> of capacitor
ε <sub>o</sub>	=	Permittivity of free space, 8.854 x $10^{-12}$ F/m
n	=	Moles
MM	=	Molecular mass
F	=	Farads
rpm	=	Rotation per minute
cm	=	Centimeter
q	=	Charge Charge
α	=	Polarizability
р	=	Dipole moments
Ν	=	Number of dipoles per cubic meter
mm	=	Millimeter
nm	5	Nanometer
$T_c$	=	Curie temperature
(C)		

# Kajian Mengenai Kesan Ultrasonification Terhadap Ciri-Ciri Fizikal Dan Elektrikal Bagi Filem Nipis Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub> Dideposit Menggunakan Kaedah Sol-Gel

#### ABSTRAK

Pencirian Barium Strontium Titanate (BST) dengan nisbah 60 kepada 40 dan nisbah 80 kepada 20 dari segi morfologi permukaan dan sifat-sifat elektrik telah dilakukan untuk menghasilkan satu campuran BST yang terbaik mengikut applikasi tertentu. Ciri-ciri Ba<sub>x</sub> Sr<sub>x</sub> TiO<sub>3</sub> dan struktur kapasitor BST telah dikaji. Satu wafer silikon jenis p berorientasikan (100) telah dideposit dengan Platinum (Pt), BST, dan Aluminium (Al) dalam susunan berikut, Si / SiO<sub>2</sub> / Pt / BST / Al. BST telah disediakan dengan menggunakan pemendapan kimia penyelesaian (CSD) di mana kaedah yang terlibat dipanggil sol-gel disebabkan oleh keupayaan untuk menghasilkannya pada kos yang rendah. Kaedah sol-gel umumnya menggunakan logam alkoxides hydrolytically yang sensitif sebagai bahan permulaan. Terdapat dua cara penyediaan untuk BST iaitu kaedah sol-gel dengan dan tanpa melibatkan ultrasonic, dan kedua-dua keputusan dibandingkan antara satu sama lain. Kesemua sampel telah melalui proses penyepuhlindapan pada suhu 800 °C di dalam suasana oksigen. Kaedah untuk penyediaan BST (60/40 dan 80/20) dijelaskan secara mendalam dan proses fabrikasi filem Bax Sr<sub>1-x</sub> TiO<sub>3</sub> diterangkan. Sampel-sampel telah diuji dalam dua kategori iaitu pencirian permukaan dan pencirian elektrik. Bagi pencirian permukaan, pembelauan sinar-X (XRD), telah digunakan untuk mengesahkan pembentukkan fasa pada darjah penteksturan. Pembentukan BST bagi setiap puncak dapat diperhatikan dan menunjukkan sampel-sampel telah menghablur dengan baek bagi kedua-dua kaedah dan nisbah. Mikroskop tenaga atom (AFM) telah digunakan untuk morfologi permukaan dalam imej topografi 2D dan 3D. Filem-filem bagi setiap nisbah amat padat, licin dan bebas retak. Dengan kenaikan nilai x bagi BST menghasilkan saiz butiran yang lebih besar dan penglibatan ultrasonic dalam kaedah penyediaan mengurangkan saiz butiran. Bagi pencirian elektrik, penganalisa parameter semikonduktor (SPA) yang diukur pada 100 kHz dengan perubahan voltan yang diberikan antara 0V kepada +5V bagi pencirian arus voltan (I-V) dan -8V kepada +8V bagi kapasitan – voltan (C-V) untuk sifat-sifat dielektrik. Kajian mikrostruktur morfologi pada permukaan sampel ini menunjukkan saiz butiran yang kurang daripada 0.1  $\mu$ m. Dengan pertambahan nilai x pada Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub>, pelbagai rantau konduksi menurun. Peningkatan pemalar dielektrik berkadar terus dengan ketebalan filem BST. Kesimpulan adalah selaras dengan keputusan yang diperolehi dengan penglibatan ultrasonic dalam langkah-langkah persediaan mengurangkan saiz butiran dan menghasilkan pemalar dielektrik dan tunabiliti yang lebih kecil.

# Investigation Of Ultrasonification Effect On Physical And Electrical Characteristics Of Ba<sub>x</sub>Sr<sub>1-x</sub>TiO<sub>3</sub> Thin Films Prepared Using Sol-Gel Method

#### ABSTRACT

The characterization of Barium Strontium Titanate (BST) with the ratio of 60:40 and 80:20 in terms of surface morphology and electrical properties to produce the best BST solution according to its various applications has been done. Properties of Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub> and the structure of BST capacitor were studied. A (100) oriented p type silicon wafer has been deposited with Platinum (Pt), BST, and Aluminium (Al) in the following order of Si / SiO<sub>2</sub>/ Pt / BST / Al. The BST was prepared using the chemical solution deposition (CSD) which involved a method called sol-gel which is of interest due to low capital investment cost. The sol-gel method generally uses hydrolytically sensitive metal alkoxides as the starting materials. There were two ways of preparation, namely the sol-gel method with and without involving ultrasonic and both of their results were compared to each other. All the samples have been annealed at 800 °C in oxygen atmosphere. The method for preparation of BST (60/40 and 80/20) was explained in detail and the fabrication process of  $Ba_x Sr_{1-x} TiO_3$  films were described. The samples were tested in two categories, namely surface and electrical characterizations. For surface characterization, X-ray diffraction (XRD) was used to confirm phase formation on the degree texturing. BST formation for every peaks were observed and show the samples were well crystallized for both methods and ratio. Atomic force microscopy (AFM) was used to study the surface morhophology in 2D and 3D topography images. The films for each ratio were very dense, smooth and crack free. With the increment of x value of BST produces larger grain size and the involvement of ultrasonic in te preparation method reduces the grain size. For electrical characterization, semiconductor parameter analyzer (SPA) measured at 100 kHz with the variation of applied voltage ranging from 0V to +5V for current – voltage (I-V) and -8V to +8V for capacitance - voltage (C-V) characteristic for its dielectric properties. Microstructural study of the surface morphology of these samples indicated grains of less than 0.1 µm in size. With the increment of x value of  $Ba_x Sr_{1-x} TiO_3$ , the range of the conduction region decreased. The dielectric constant increase proportional to the thickness of BST films. Conclusion is consistent with the result obtained which with involvement of ultrasonic in the preparation steps reduces the grain size and produces smaller dielectric constant and tunability.

#### LIST OF PUBLICATIONS

- Hatta R. M., Juhari N., and Adnan J. (2009). Preparation of Ba<sub>0.5</sub>Sr<sub>0.5</sub>TiO<sub>3</sub> ferroelectric thin films deposited by the sol-gel method with ultrasonic and reflux technique. 25<sup>th</sup> Regional Conference on Solid State Science & Technology 2009.
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- Retnasamy V., Poopalan P., Sauli Z., Yaacob S., Nor Haimi W. M. W., Taniselass S., Ramli N., Aziz M. H. A., Hatta R M., Man B., Saif A. A. (2010). Optical Face-Contour Analysis O. F. C. A. 21<sup>st</sup> International Invention, Innovation and Technology Exhibition (ITEX) 2010.

#### **CHAPTER ONE**

#### **INTRODUCTION**

#### **1.1** Research introduction

This chapter briefly reviews and explains the research problem and the overview of the barium strontium titanate. The research objectives, scopes and approaches are explained in detail in this chapter including the thesis layout.

# **1.2** Overview of the barium strontium titanate

Barium strontium titanate ( $Ba_x Sr_{1-x} TiO_3$ ) thin films have been investigated as potential candidates for ferroelectric and dielectric materials. The properties depend on the x-value of the barium and strontium (Park et al., 2001). Valasek (1921) has reported that the spontaneous dipole moment in Rochelle salt can be reoriented by an external electric field. Jaffe et al. (1971) indicated that in the early 1940's, critical steps were taken in understanding piezoelectricity and ferroelectricity with the work on BaTiO<sub>3</sub> which led to the discovery of the unusually large dielectric constant. The discovery that this high value was due to ferroelectricity and the reorientation of the dipoles with a process called poling. In 1978, Raytheon R&D group, then part of Texas Instruments, patented ferroelectronic infrared detectors, using barium strontium titanate. The BST was coated over the thermal imager's sensor (Bullard Company, 2011).

Kil et al. (1997) stated that barium strontium titanate (BST), lead zirconate titanate (PZT) and strontium titanate (STO) are typical high dielectric constant materials. Among them, BST which is a solid solution consisting of barium titanate (BaTiO<sub>3</sub>) and strontium titanate (SrTiO<sub>3</sub>) is the most attractive materials for high density DRAM application. This is because of it's paraelectric phase at the device operating temperature.

Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub> have been chosen among researchers who study its electrical properties, high dielectric constant and composition dependent Curie temperature ( $T_c$ ) in these past years (Roy & Krupanidhi, 1993). The Curie temperature,  $T_c$  of Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub> decreases linearly with the increasing amount of strontium in BaTiO<sub>3</sub> lattice. Liu et al. (2004) found that ferroelectric **BST** ceramics with perovskite structure, posses a large temperature coefficient of dielectric constant (TCD) around their Curie temperature. Furthermore,  $T_c$  can be easily varied from 0 to 70 °C by adjusting the ratio of Ba and Sr. This characteristic indicates the transition of the BST from ferroelectric phase into paraelectric phase. Yamamichi et al. (1994) reviewed electrical properties of Ba<sub>x</sub> Sr<sub>1-x</sub> TiO<sub>3</sub> which were varied continuously with a molar ratio from 0 to 1.

Most of the experiments which have been done were intended to improve the dielectric properties by increasing substrate temperature, optimizing sputtering condition and so on (Wang, 1996). There are several different techniques used to fabricate the barium strontium titanate including sputtering (Horikawa, Mikami & Makita, 1993), laser ablation (Saha & Krupanidhi, 2000), metal organic chemical vapor deposition (MOCVD) (Catalan,

Mantese & Micheli, 1994) and sol-gel processing (Lahiry, Gupta & Sreenivas, 2000). Among all the techniques that have been stated, sol-gel processing is the most attractive due to low processing temperature (compatible with Si processing), high purity of BST, easier composition control, easier fabrication of large area films and the low cost for preparing the solution and purchase of equipments, which definitely make the sol-gel as the chosen technique for this work.

#### 1.3 **Research problem**

malcopyright During this era, almost all parts of the world have been changed by science and technology. Every single thing is changed according to desire and current needs. The same goes to electronic circuits. With ever-increasing development and usage in electronic systems, the continuous miniaturization of electronic circuits has also rapidly increased. Size and functionality are always in parallel with time and technology. Furthermore, new materials need to be produced and the methods can be modified according to the needs of the industry. Barium strontium titanate however has been chosen as the material for the work, due to its potential in the area of ferroelectric and piezoelectric applications.

In this work, two methods of barium strontium titanate preparations, in two ratios namely 60:40 and 80:20 which are sol-gel prepared involving ultrasonic and without involving ultrasonic. The sol-gel method involving ultrasonic has been used in previous researches (Zhang et al., 2006). Investigation on the effect of ultrasonic has been done (Abe et al., 2010). To the best of the author's knowledge, there were very few previous works related to the effect of ultrasonic in term of BST preparation (Chung et al., 2001; Zhang et al., 2006; Abe et al., 2010).

Based on the theories of ultrasonic effects on crystallization in the literature, there are two major hypotheses; first hypothesis states that ultrasonic can assist the crystallization process in several ways, influence the initiation of crystal nucleation and ensuring small and even-sized crystals are formed (Clark, 2008). The second hypothesis claimes that ultrasonic wave traveling through a liquid consists of alternate compressions and rarefactions thus, if the wave is high enough in amplitude, cavitation will occur and disrupt the structure (Howard, 1975). Taking the above hypothesis into consideration, detailed analysis and characterization has to be done for BST crystallization under the influence of ultrasonic factor. The effect of ultrasonic to the crystallization of BST needs to be determined whether it is constructive or destructive in nature. othisitemisprote

### 1.4 Research objectives

The main objective of this project is to improve the current BST thin film in terms of surface and electrical properties through the sol-gel method. The effect of ultrasonification is considered. In order to achieve the main objectives, sub-objectives as detailed below were addressed:

- To study and investigate two methods of  $Ba_x Sr_{1-x} TiO_3$  preparation of which the sol-gel was prepared involving ultrasonic and without involving ultrasonic.
- The layers of  $Ba_{0.6}$   $Sr_{0.4}$  TiO<sub>3</sub> and  $Ba_{0.8}$   $Sr_{0.2}$  TiO<sub>3</sub> solution were deposited on Si/SiO<sub>2</sub>/Pt and subsequently annealed at temperature of 800°C. XRD analysis also has to be implemented to verify the BST solution.
- To study the physical and electrical properties of BST and compare these two methods of sol-gel preparation in term of XRD peaks, AFM results, I-V, C-V and leakage current density.

#### 1.5 **Research scope**

In this research, barium strontium titanate thin films were prepared using the sol-gel method. However, an additional technique using ultrasonicator was added. The differences between the two methods in term of surface structure and electrical characterization were studied and investigated. The BST solution was deposited using the spin coating process. The structure of metal-ferroelectric material-metal was been fabricated. Two metal plates which consist of Aluminium (Al) and Platinum (Pt) were used. Pt was used as a bottom electrode while Al was used as the top electrode. Both metal plates were deposited using the sputtering technique in order to study the electrical properties of Ba<sub>0.6</sub> Sr<sub>0.4</sub> TiO<sub>3</sub> and Research approach sected by orient Ba<sub>0.8</sub> Sr<sub>0.2</sub> TiO<sub>3</sub>.

# 1.6

This thesis discusses and analyzes the structure, process and property of thin film layers. A high quality ferroelectric thin film that can be used to power up small electronic or electrical devices such as pH meter. Electrical properties of BST for instance pyroelectric can be used to convert from heat to electricity. In addition, Chemical Solution Deposition (CSD) methods of BST thin films and sputtering process are discussed to provide better understanding for future processing and formation of higher quality of BST thin film. A calculation of mol is needed to make sure a BST with the ratio of 60/40 and 80/20 can be produced. Ultrasonicator was used and the step added into sol-gel method to disperse the barium acetate and strontium acetate powder inside the solution. This technique make common because it produced smaller grains to achieve smoother surface